

Substitute Form PTO-1449
(Modified)**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

(37 CFR §1.98(b))

U.S. Department of Commerce
Patent and Trademark Office

Attorney's Docket No.

07977-263001-US4563

Application No.

09/760,499

Applicant

Yamazaki, et al.

Filing Date

January 11, 2001

Group Art Unit

1733

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AQ	Shimoda, et al., "Surface Free Technology by Laser Annealing (SUFTLA)", IEEE, 1999 (4 pages).
	AR	Duplicate see paper no. 5
	AS	
	AT	

Examiner Signature

John DW

Date Considered

2/21/03

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 07977/263001/US4563	Application No. Unknown
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Yamazaki, et al.	
		Filing Date Filed Herewith	Group Art Unit

 09/760499
 01/11/01

U.S. Patent Documents

Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
92	AA	5,757,456	5/26/98	Yamazaki, et al.			
1	AB	5,821,138	10/13/98	Yamazaki, et al.			
	AC	5,834,327	11/10/98	Yamazaki, et al.			
92	AD	6,118,502	9/12/00	Yamazaki, et al.			
	AE						
	AF						
	AG						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
92	AH	8-96959	4/12/96	Japan			Abstract only	
	AI	9-63770	3/7/97	Japan			Abstract only	
	AJ	9-312260	12/2/97	Japan			Abstract only	
	AK	10-247735	9/14/98	Japan			Abstract only	
	AL	10-270363	10/9/98	Japan			Abstract only	
	AM	11-191628	7/13/99	Japan			Abstract only	
	AN	8-254686	10/1/96	Japan			Abstract only	
92	AO	8-288522	11/1/96	Japan			Abstract only	

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
92	AP	Shimoda, et al., "Surface Free Technology by Laser Annealing (SUFTLA)", IEDM Technical Digest, 1999, pp.289-292.
	AQ	
	AR	
	AS	

Examiner Signature <i>John SH</i>	Date Considered 2/24/03
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